



## Laser Micro/Nano Fabrication, Second Edition

Guest Editor:

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Deadline for manuscript  
submissions:

**closed (30 November 2025)**

### Message from the Guest Editor

Dear Colleagues,

I invite you to contribute to this Special Issue, which seeks research and review articles on laser micro/nanofabrication techniques. These include but are not limited to (1) new laser-based approaches to fabricate micro/nanostructures, (2) subtractive methods, precision laser ablation and cutting, (3) additive methods and laser-induced deposition, (4) laser bonding, welding, and the formation of components; (5) novel software, CAD, and nanometer precision hardware for direct laser writing, and (6) potential research and industrial applications in optical, electronic, and biological fields. Laser micro/nanofabrication is rapidly becoming a preferred manufacturing method due to its inherent high precision, mask-less nature, and rapid processing speed. This Special Issue aims to feature the latest developments in various applications of laser micromachining.

Dr. Thomas C. Hutchens

*Guest Editor*





## Editor-in-Chief

## Message from the Editor-in-Chief

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